

<b>Notice of References Cited</b>	Application/Control No. 10/086,614		Applicant(s)/Patent Under Reexamination MIRKARIMI ET AL.	
	Examiner Wesley D Markham		Art Unit 1762	Page 1 of 1

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	V	Spiller, "Smoothing of multilayer x-ray mirrors by ion polishing", Appl. Phys. Lett., Vol.54, Number 23, pages 2293-2295, June 1989			
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\*A copy of this reference is not being furnished with this Office action. (See MPEP § 707.05(a).)  
Dates in MM-YYYY format are publication dates. Classifications may be US or foreign.